

ATTACHMENT 3

SAMPLING, ANALYTICAL, AND QA/QC PROCEDURES

Consisting of:

- o U.S. Army Chemical Materials Agency (CMA) Programmatic Laboratory and Monitoring Quality Assurance Plan (LMQAP), Final, June 2004, incorporated by reference.
- o Laboratory Quality Control Plan, CDRL L005/CDRL 024, Revision 6, Change 1, July 2005, incorporated by reference.

Enclosure 1	Laboratory Operating Procedure for Depot Area Air Monitoring Systems (DAAMS), TE-LOP-522, Revision 7, Change 1, September 16, 2005.
Enclosure 2	Laboratory Operating Procedure for Automatic Continuous Air Monitoring System (ACAMS), TE-LOP-524, Revision 8, Change 2, September 16, 2005.
Enclosure 3	Laboratory Operating Procedure for Liquid and Dry Solid Residue Sampling TE-LOP-534, Revision 5, Change 4, May 2, 2005.
Enclosure 4	Laboratory Operating Procedure for V/G Conversion Pad Assembly TE-LOP-528, Revision 4, Change 3, September 16, 2005.
Enclosure 5	RESERVED
Enclosure 6	Laboratory Operating Procedure for Analysis of Depot Area Air Monitoring System (DAAMS Tubes). TE-LOP 562, Revision 6, Change 6, October 2005.
Enclosure 7	Laboratory Operating Procedure for Extractions/Analyses TE-LOP-572, Revision 4, Change 4, March 15, 2006.
Enclosure 8	Laboratory Operating Procedure for Special Analysis, TE-LOP-574, Revision 6, Change 4, May 11, 2006.
Enclosure 9	Laboratory Operating Procedure for Neat Agent Operation and Gas Chromatographic Determination of Concentration of Agent Standards, TE-LOP 584, Revision 9, March 15, 2006.
Enclosure 10	QC Procedures for Monitoring Operations, TE-LOP-592, Revision 3, Change 3, May 2, 2005.
Enclosure 11	QC Procedures for Analytical Operations, TE-LOP-594, Revision 5, Change 2, May 2, 2005.
Enclosure 12	RESERVED
Enclosure 13	RESERVED
Enclosure 14	Analysis of Metals by Inductively Coupled Plasma-mass Spectrometry (ICP-MS), TE-LOP-557, Revision 0, Change 7, September 23, 2005.

**All Enclosures Are Incorporated By Reference
See DSHW to Arrange An Appointment to Review**